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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/626,096	07/23/2003	Seung-Jae Lee	2522-022	9000
759	90 02/22/2005		EXAMINER	
MARGER JOHNSON & McCOLLOM, P.C. 1030 S.W. Morrison Street			VU, DAVID	
Portland, OR	-5011 211001		ART UNIT	PAPER NUMBER
			2818	
			DATE MAILED: 02/22/2005	3

Please find below and/or attached an Office communication concerning this application or proceeding.

			11.0		
	Application No.	Applicant(s)	H'A		
	10/626,096	LEE ET AL.			
Office Action Summary	Examiner	Art Unit			
	DAVID VU	2818			
The MAILING DATE of this communication a Period for Reply	ppears on the cover sheet w	ith the correspondence address			
A SHORTENED STATUTORY PERIOD FOR REF THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a r - If NO period for reply is specified above, the maximum statutory peri - Failure to reply within the set or extended period for reply will, by stated that the period for reply will be set or extended period for reply will, by stated that the period for reply will be set or extended period for reply will, by stated that the period for reply will, by stated that the period for reply will be set or extended period for reply will, by stated that the period for reply will be set or extended period for reply will be set	N. 1.136(a). In no event, however, may a reply within the statutory minimum of thi od will apply and will expire SIX (6) MOI tute, cause the application to become A	reply be timely filed rty (30) days will be considered timely. NTHS from the mailing date of this communication BANDONED (35 U.S.C. § 133).	n.		
Status					
1) Responsive to communication(s) filed on 23	3 July 2003.				
,	·				
•	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is				
closed in accordance with the practice unde	er Ex parte Quayle, 1935 C.I). 11, 453 O.G. 213.			
Disposition of Claims					
4) ⊠ Claim(s) <u>1-16</u> is/are pending in the applicati 4a) Of the above claim(s) is/are withd 5) □ Claim(s) is/are allowed. 6) ⊠ Claim(s) <u>1-7 and 9-16</u> is/are rejected. 7) ⊠ Claim(s) <u>8</u> is/are objected to. 8) □ Claim(s) are subject to restriction and	Irawn from consideration.				
Application Papers					
 9) The specification is objected to by the Exam 10) The drawing(s) filed on 23 July 2003 is/are: Applicant may not request that any objection to the Replacement drawing sheet(s) including the corrupt of the oath or declaration is objected to by the 	a) accepted or b) objee the drawing(s) be held in abeyarection is required if the drawing	ince. See 37 CFR 1.85(a). g(s) is objected to. See 37 CFR 1.121(d	d).		
Priority under 35 U.S.C. § 119					
12) Acknowledgment is made of a claim for fore a) All b) Some * c) None of: 1. Certified copies of the priority docume 2. Certified copies of the priority docume 3. Copies of the certified copies of the p application from the International Bur * See the attached detailed Office action for a	ents have been received. ents have been received in a priority documents have been reau (PCT Rule 17.2(a)).	Application No n received in this National Stage			
Attachment(s) 1) Notice of References Cited (PTO-892)		Summary (PTO-413)			
 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/Paper No(s)/Mail Date 04/01/04. 		(s)/Mail Date Informal Patent Application (PTO-152)			

DETAILED ACTION

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

1. Claims 1-4 and 10-16 are rejected under 35 U. S. C. 102(b) as being anticipated by Chang et al. (US Pat. 6,180,454, herein after Chang).

Regarding claims 1 and 4, Chang (See ABSTRACT) disclose a method for forming an electrode, comprising: forming a polysilicon layer (second poly layer/poly 2/control gate) on a semiconductor substrate; forming an amorphous silicon capping layer on the polysilicon layer (col. 5, lines 34-36); and depositing a silicide layer on the capping layer (col. 6, lines 6-13).

Regarding claims 10, 12 and 15, Chang (See ABSTRACT) disclose a semiconductor memory device, comprising: a gate oxide layer formed on a semiconductor substrate; a floating gate electrode (first poly layer) formed on the gate oxide layer, an intergate dielectric layer (insulating layer/ONO) formed on the floating gate electrode; a polysilicon layer (second poly layer/poly 2/control gate) on a semiconductor substrate; an amorphous silicon capping layer on the polysilicon layer (col. 5, lines 34-36); and a silicide layer on the capping layer (col. 6, lines 6-13).

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Regarding claims 2, 3, 11, 14 and 16, Chang disclose the silicide layer (tungsten silicide) is formed using a dichlorosilane (SiH₂Cl₂) gas (col. 6, lines 6-13), and wherein the capping layer (poly 2) is formed to have a thickness from about 1000-1400A (sufficient to prevent chlorine ions dissociated from the dichlorosilane (SiH₂Cl₂) gas from diffusing toward the polysilicon layer) (col. 6, lines 2-3)

Regarding the limitation "wherein the polysilicon layer is formed by crystallizing amorphous silicon" (claim 13) or "wherein the tungsten silicide layer is formed using dichlorosilane" (claim 15), such limitation does not further define the structure as instantly claimed, nor serve to distinguish over Hasegawa. Note that a "product by process" claim is directed to the product per se, no matter how actually made, In re Hirao, 190 USPQ 15 at 17 (footnote 3). See also In re Brown, 173 USPQ 685; In re Luck, 177 USPQ 523; In re Fessmann, 180 USPQ 324; In re Avery, 186 USPQ 161; In re Wertheim, 191 USPQ 90 (209 USPQ 554 does not deal with this issue); In re Marosi et al, 218 USPQ 289; and particularly In re Thorpe, 227 USPQ 964, all of which make it clear that it is the patentability of the final product per se which must be determined in a "product by process" claim, and not the patentability of the process, and that an old or obvious product produced by a new method is not patentable as a product, whether claimed in "product by process" claims or not. Note that applicant has the burden of proof in such cases, as the above caselaw make clear.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

2. Claims 5-7 and 9 are rejected under 35 U.S.C. 103 (a) as being unpatentable over Chang (US Pat. 6,180,454) in view of Oka et al. (US Pat. 6,235,563, herein after Oka)

Regarding claims 5 and 9, Chang (See ABSTRACT) disclose a flash memory device involving the steps of forming a gate oxide layer formed on a semiconductor substrate; a floating gate electrode (first poly layer) formed on the gate oxide layer; an intergate dielectric layer (insulating layer/ONO) formed on the floating gate electrode; a polysilicon layer (second poly layer/poly 2/control gate) on a semiconductor substrate; an amorphous silicon capping layer on

the polysilicon layer (col. 5, lines 34-36); and a silicide layer on the capping layer (col. 6, lines 6-13).

Chang fails to disclose the polysilicon layer of the control gate (poly 2) is formed by an amorphous silicon layer then annealing the amorphous silicon layer to form a polysilicon layer. However, Oka teaches a polycrystalline film (polysilicon) with high purity has been obtained by performing solid phase recrystallization on an amorphous silicon film formed by annealing the amorphous silicon film in a nitrogen atmosphere (See ABSTRACT). It would have been obvious to one of ordinary skill in the art at the time of the invention to use the annealing process of Oka in the method of Chang, because it would have provided the advantageous /benefit of forming a polycrystalline thin films having high polycrystalline quality, larger crystal grains and good crystal grain orientation.

Regarding claims 6 and 7, Chang disclose the silicide layer (tungsten silicide) is formed using a dichlorosilane (SiH₂Cl₂) gas (col. 6, lines 6-13), and wherein the capping layer (poly 2) is formed to have a thickness from about 1000-1400A (col. 6, lines 2-3).

Allowable Subject Matter

3. Claim 8 is objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

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Conclusion

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to David Vu whose telephone number is (571) 272-1798. The examiner can normally be reached on Monday-Friday from 8:00am to 5:00pm. If attempt to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Nelms can be reached on (571) 272-1787. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR, Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

David Vu

February 17, 2005.

Dribared